



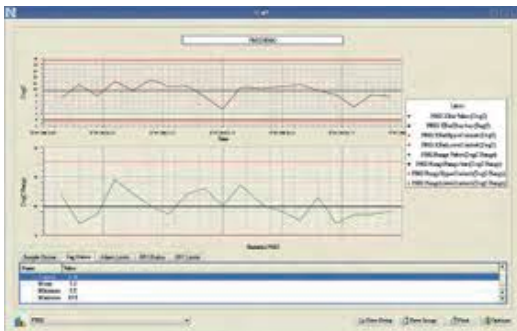
® Knowledge Beyond Measure.

Facility Monitoring Software For Electronic and Semiconductor Applications



Ensure Contamination Control With FMS-5

For electronics, semiconductor, hard disk drive, and other applications, FMS-5 assists in maintaining contamination control of critical manufacturing processes. FMS-5 comes with built-in Statistical Process Control (SPC) tools, SPC parameters can be defined for Upper Control Limits, Lower Control Limits, mean crowding, alarm number, and trend number. Control charts can be generated by utilizing FMS-5's graphing function and can aid in providing proactive predictive alarms to help alleviate issues before they arise. For defined sample points, detailed SPC information is displayed when accessed via the statistic function. FMS-5 provides a complete, statistical monitoring system with the data integrity needed to ensure optimal facility output.



Example of SPC charts in FMS-5

Robust Facility Monitoring Software

TSI FMS system is an advanced, reliable, and user-friendly, monitoring software suite that features a truly open architecture, supporting multiple instruments. Typical inputs include:

- Airborne particle counters
- Differential pressure gauges
- ESD
- Temperature and humidity sensors
- Liquid particle counters
- Airborne molecular contamination and more

Features and Benefits

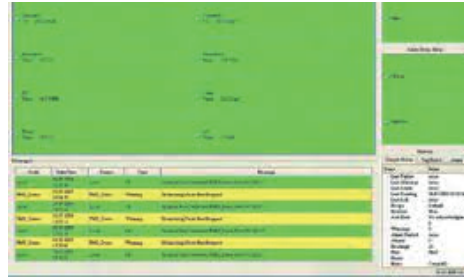
- Open architecture
- SPC control charts
- Unique Buddy automatic hot standby option
- Logs events and alarms
- Back up via mirror database
- Multi-level maps
- Display and auto reporting
- Group, acknowledgement and auto alarms
- Controls multi-point monitoring systems
- Real-time data
- Graphs of information vs time to identify trends
- Built-in system redundancy
- Intuitive operation
- Easy data export
- User defined reporting
- Notifications via email, SMS, and telephone

Facility Monitoring Software For Electronic and Semiconductor Applications



Ease of Use

An intuitive, user configurable interface means immediate visibility of real-time data. Single mouse click access to historical data and report generation leads to reduced operator training, immediate data access and improved process control.



Graphing & Reporting

FMS comes with its own report generation tool. This allows users to create customized reports to meet your needs. Where more advanced reporting is required, third party tools can be easily deployed to use with FMS-5 databases. All collected data can be turned into useful process information via powerful FMS-5 reporting and graphing tools. Critical reports can be generated each day, and auto reports can be created based on recorded events.



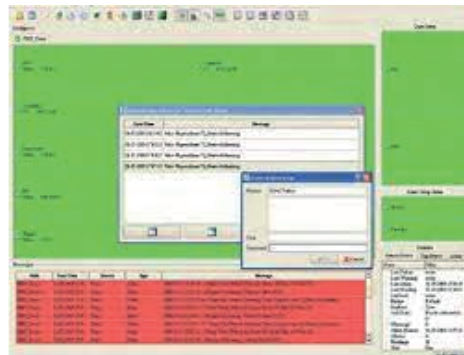
Mapping

Multi-level maps display the last recorded value for each instrument and show real-time icons in Red for Alarm, Yellow for Warning, Green for Okay and Blue for Instrument Failure. Simply click on the instrument icon for instant, detailed information.



Communication

FMS-5 supports multiple system outputs like beacons, sounders, SMS text, email, auto-dialers and reporting are supported. Operators and managers are immediately informed of an event. This information aids in root cause investigations, process validation and improved product quality.



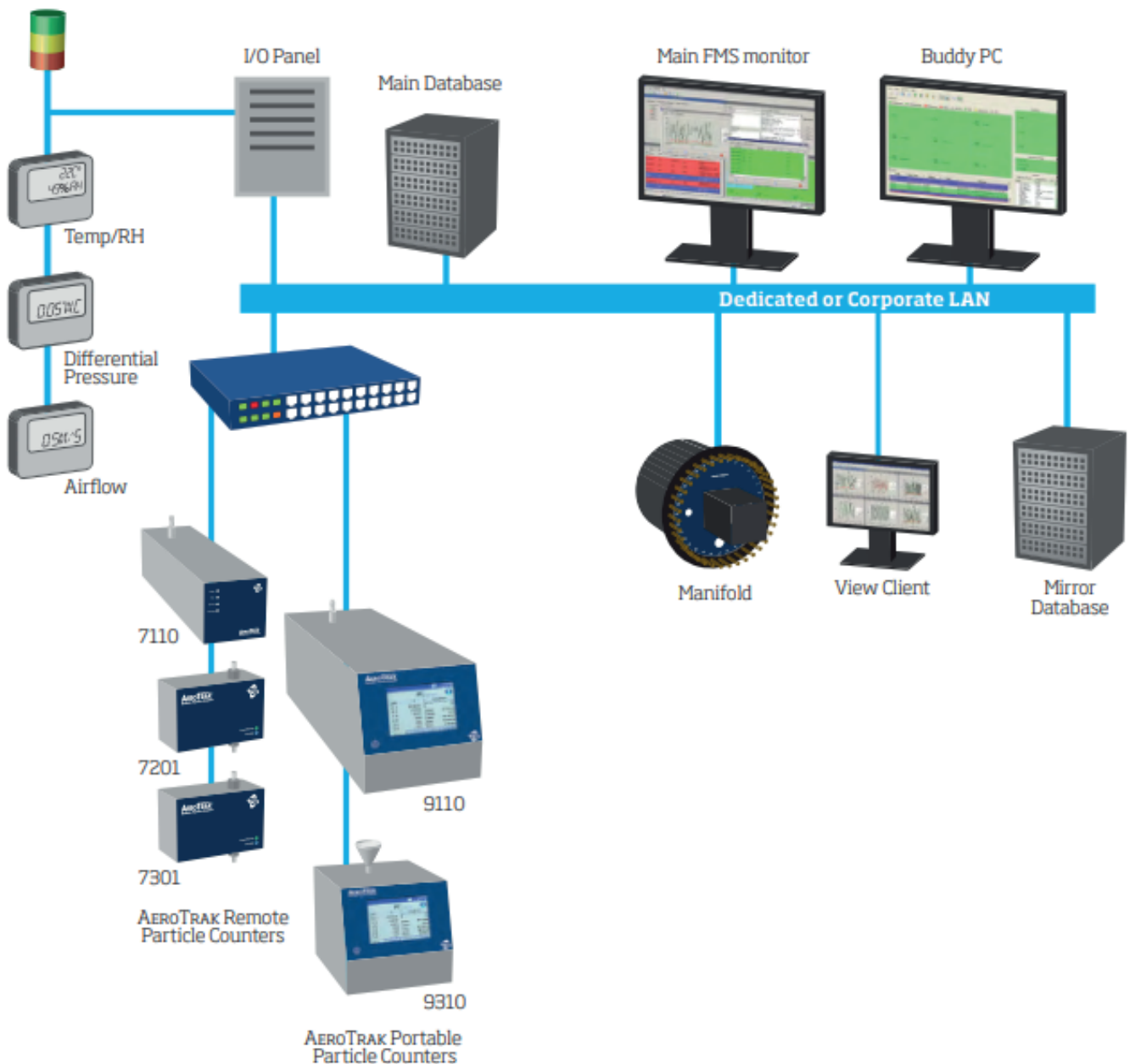
Need a Buddy?

FMS offers a unique Buddy (Automatic Hot Standby) system option for built-in system redundancy. This completely integrated back-up system resides on an alternate computer. If anything happens to the primary FMS-5 system, the Buddy automatically takes over, continuing to collect secure data. No manual intervention is required in the event of a computer failure, meaning no system down time, no lost validated data, and peace of mind.

Facility Monitoring Software For Electronic and Semiconductor Applications



Facility Monitoring System Overview



TSI, and the TSI logo are registered trademarks of TSI Incorporated.